

## IN THE SPECIFICATION:

Please amend the specification as follows:

On page 7, line 13, please replace the paragraph:

Two alternate configurations for the apparatus are presented in **FIGS. 2 and 3**. **FIG. 2** shows a schematic cross-sectional elevation view of a first fast single-wafer megasonic cleaning apparatus **200** made in accordance with the present invention. **FIG. 3** shows a schematic cross-sectional elevation view of a second embodiment of a fast single-wafer megasonic cleaning apparatus **200** made in accordance with the present invention. The second embodiment shown in **FIG. 2** uses a smaller footprint to reduce the floor area the tool occupies. In both **FIGS. 2 and 3**, the apparatus **200** includes a container **205** for holding single wafer **90** to be cleaned and for holding the liquid cleaning medium **220**, and a megasonic transducer **210** disposed to face the surface of single wafer **90** to be cleaned. Megasonic energy is directed **270** from megasonic transducer **210** toward the surface of single wafer **90** to be cleaned. As described herein below, conventional prior art megasonic transducers, such as those used in the batch ultrasonic cleaning system of **FIG 1**, are available as an array of megasonic transducers. Such an array of megasonic transducers is more clearly shown in the top view of **FIG. 8b** as it is applied to the single wafer embodiment of the present invention. As further shown in **FIG. 8b**, lower array of megasonic transducers **210a'** is larger than single wafer **90**. From the active surface of each megasonic transducer of the array, megasonic energy is directed at wafer **90**, as also shown in FIGS. 2, 3, 7, and 8a. In the systems illustrated in FIGS. 2, 3, 7, 8a, and 8b substantially all vibration provided in liquid cleaning medium 220 is from megasonic transducer 210, 210a, 210b, 210a', or 210b', which are all oriented substantially parallel to the surface of single wafer 90. Sidewalls extend on all sides of container 205. However, while individual transducers of the array transmit their energy at various angles, no transducer having an active surface facing perpendicular to the active surface of transducer 210 is provided, as shown in FIGS. 2, 3, 7, 8a, and 8b and no substantially comparable amount of energy is therefore provided from such a perpendicularly oriented transducer. The apparatus is arranged so that liquid cleaning medium **220** has a free liquid surface **250**, and the liquid flow is shown in **FIGS. 2 and 3** by flowlines **245** within container **205**, by inlet flowlines **240**, and by overflow outlet flowlines **260**, showing that the liquid cleaning medium **220** overflows the container, flowing over overflows 260.